

# ***DEVELOPMENT OF MEMS BASED MICROPUMPS FOR MEDICAL APPLICATIONS***

BY

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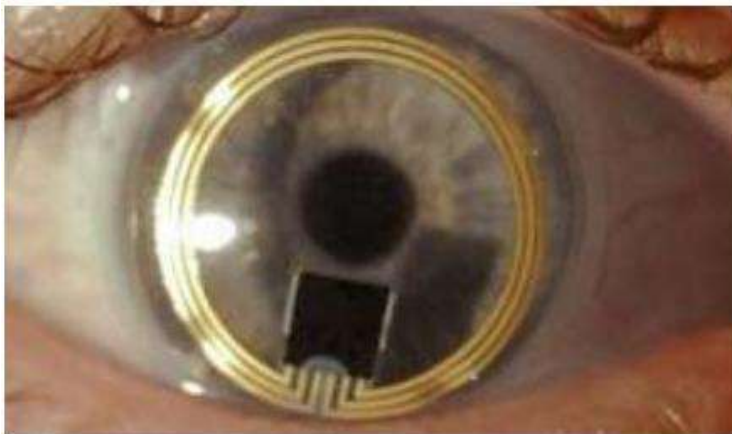
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# INTRODUCTION

- ▶ MEMS is termed as Micro-Electro-Mechanical Systems.
- ▶ MEMS have been an important aspect in different domains of technological advancements.
- ▶ Application of MEMS in medical domain has been elevated in recent years for sensing and actuation purposes.
- ▶ But, there has been a **dearth of MEMS based devices** for fast and **effective treatment of wounds** and also for **real time treatment of glaucoma**.



[http://www.eeherald.com/section/design-guide/mems\\_medical.html](http://www.eeherald.com/section/design-guide/mems_medical.html)

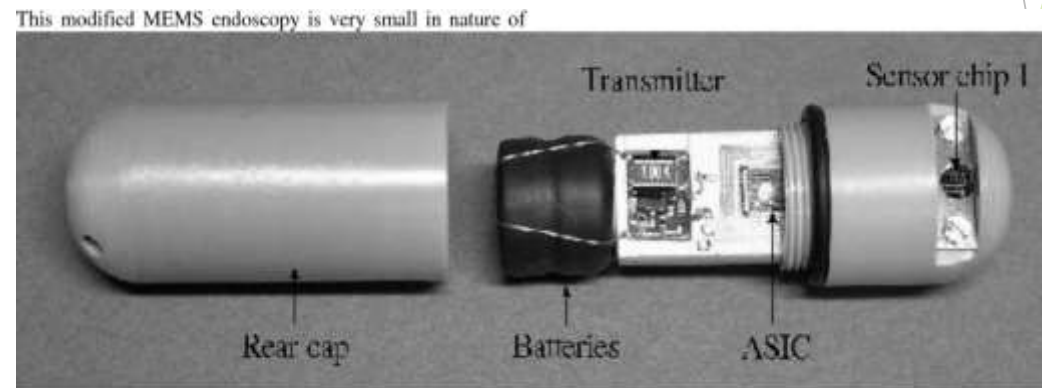


Figure 2: Lab on a pill

Abba, Ibrahim A.. "Role of Microelectromechanical Devices in Improving Human Health." (2015).

# WOUND THERAPY

- ▶ Vacuum Assisted Closure or Negative-pressure wound therapy.
- ▶ How does it work?
  - i. Device **decreases air pressure** on the wound. The gases in the air around us put pressure over the area of the wound.
  - ii. Induce mechanical **stress** to tissues and stimulate the **division of cell (Mitosis)**
  - iii. Speed of the **growth of new blood vessels** can be enhanced by **removing excess exudates** and wound will be drawn **closed toward the center point**.

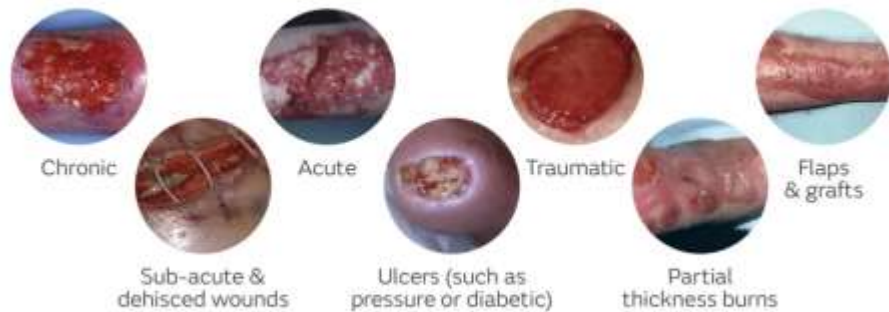


Figure : NPWT Wound Types and treatment.  
Credit: <https://www.smith-nephew.com/>

MEMS based micropumps

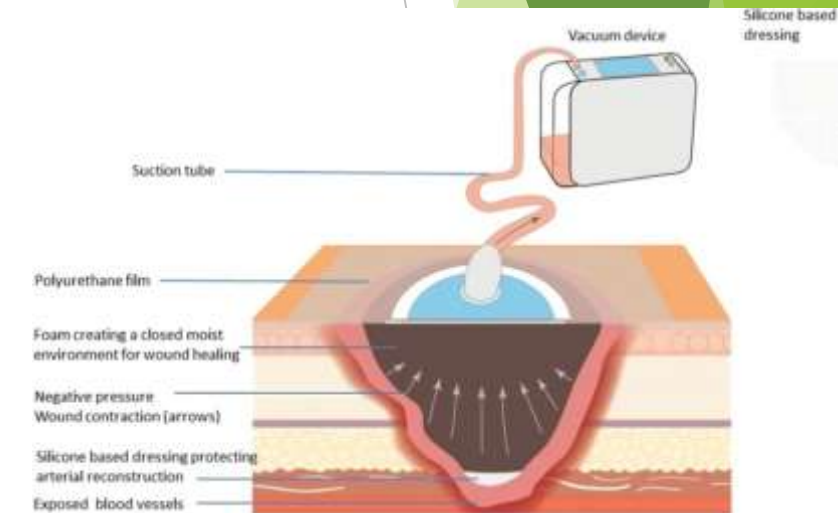


Figure: Operation of NPWT  
Credit: S. Andersson, C. Monsen, S. Acosta, Outcome and Complications Using Negative Pressure Wound Therapy in the Groin for Perivascular Surgical Site Infections after Vascular Surgery, 2017

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# GLAUCOMA

- ▶ Worldwide 6 - 9% blindness is caused by glaucoma.
- ▶ In 2020, 76 million people to 111.8 million in 2040 can be affected
- ▶ Normal range of IOP ~ 18-21 mm Hg for human eye
- ▶ Increased IOP damages optic nerves.
- ▶ Two types of glaucoma - open-angle glaucoma, angle-closure glaucoma
- ▶ Implantation - open-angle - in between cornea and Iris, angle-closure - in between Iris and Lens

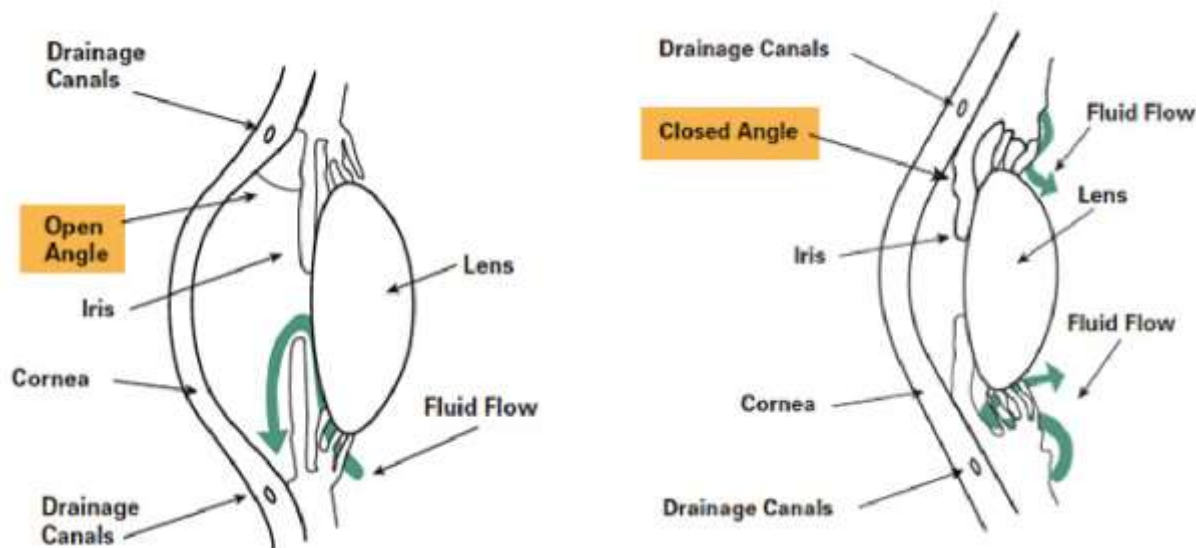


Figure: Open Angle and Closed angle Glaucoma  
Credit: <http://www.glaucoma.org/glaucoma/>.

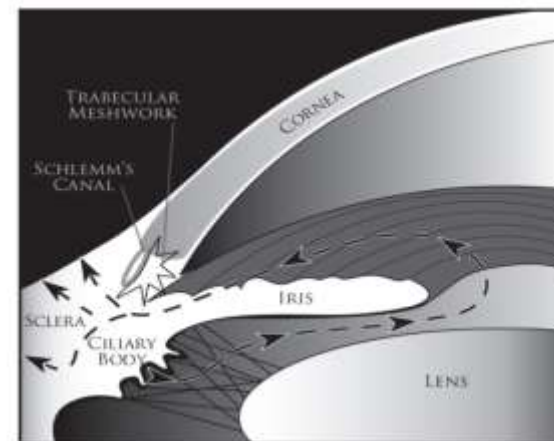
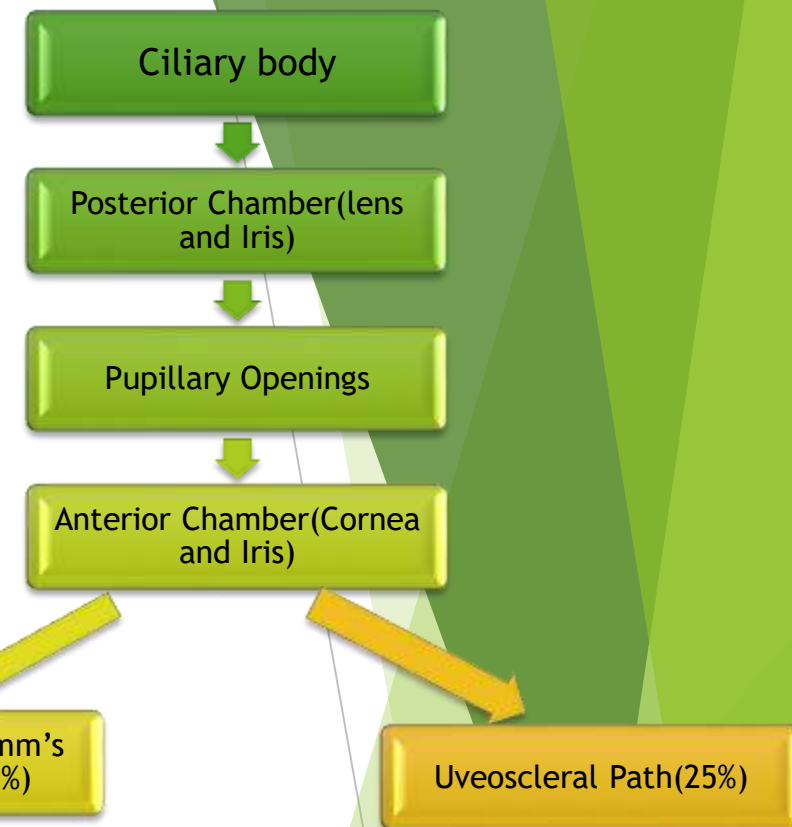


Figure: trabecular meshwork path  
Credit: Aqueous Humor Dynamics Manik Goel

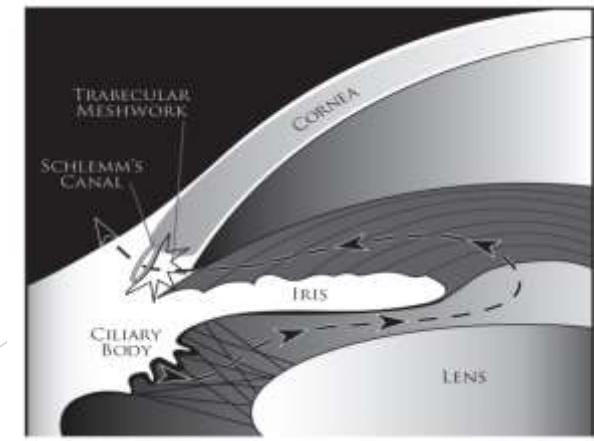


Figure: Uveoscleral path  
Credit: Aqueous Humor Dynamics Manik Goel



# TARGET OF THE PROJECT

- ▶ There are **no devices** to mitigate or heal the wounds inside the body.
- ▶ There are **no devices** to measure real time pressure and self actuate to pump out intraocular fluid to relieve IOP causing Glaucoma.
- ▶ To strike the problem of **in-vivo wounds** a **micropump is to be designed**, which will remove the exudates and to keep the wound clean and help fast healing of the wound.
- ▶ A **sensor** will also be incorporated to check the **real-time vitals** of the patient.
- ▶ For Glaucoma, **micropump** with **integrated pressure sensor** to be designed which **self-actuates**.
- ▶ The **micropumps** should be of **compact size** in the order of millimetres to centimetres.
- ▶ **Fabrication** of the devices will be done to be ready for implementation.

# DESIGN OF MEMS BASED WOUND THERAPY SYSTEM

- ▶ The **schematic** of the design of MEMS based wound therapy system is shown.
- ▶ A **power source** is applied to the system. The whole pumping mechanism is **controlled** by a **control system**.
- ▶ **After pumping** the exudates are taken out of the system for further operations.

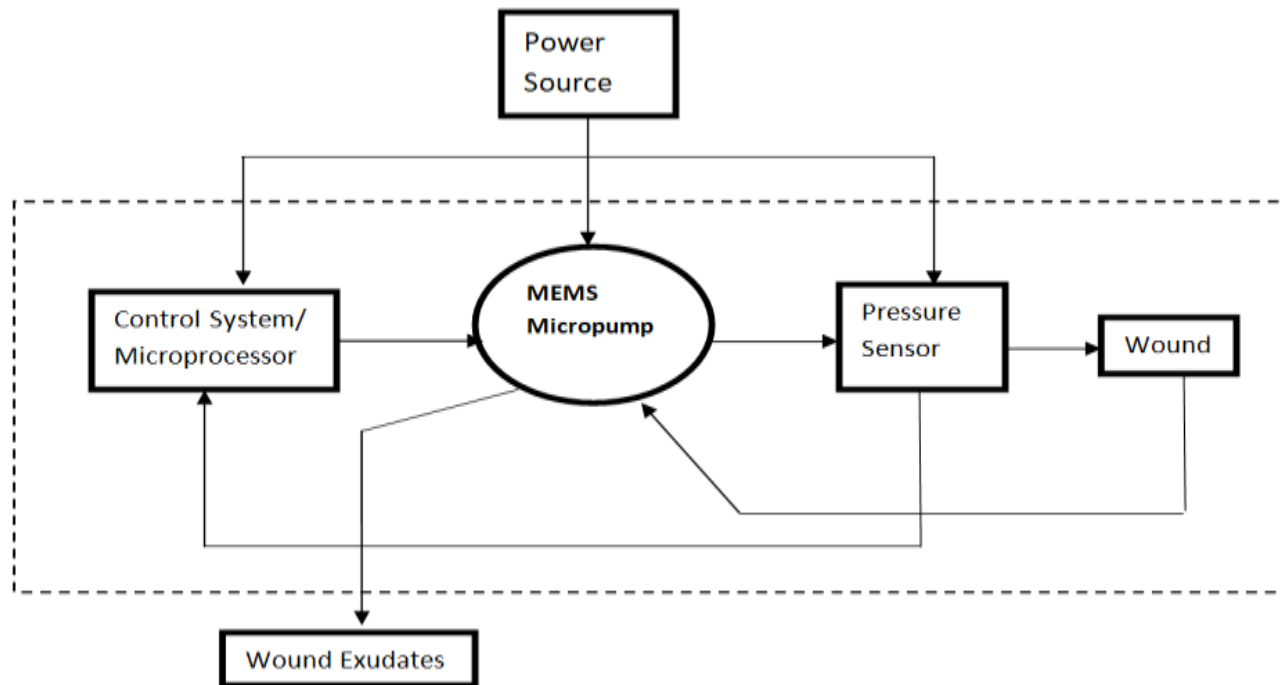


Figure : overall design of the system

## MEMS based micropumps

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# DESIGN OF NOZZLE DIFFUSER MICROPUMP

## Structure Schematic

- ▶ The structure shows **two conical diffuser elements** with **fully developed inlet chamber**.
- ▶ The fluid goes in the inlet, through the chamber and gets pumped out through the outlet
- ▶ The chamber is covered by a actuator which changes the pressure inside the chamber thus actuating the pumping action.
- ▶ The designed micropump is shown below.
- ▶ The micropump is of size **1.2cm\*0.6cm**.

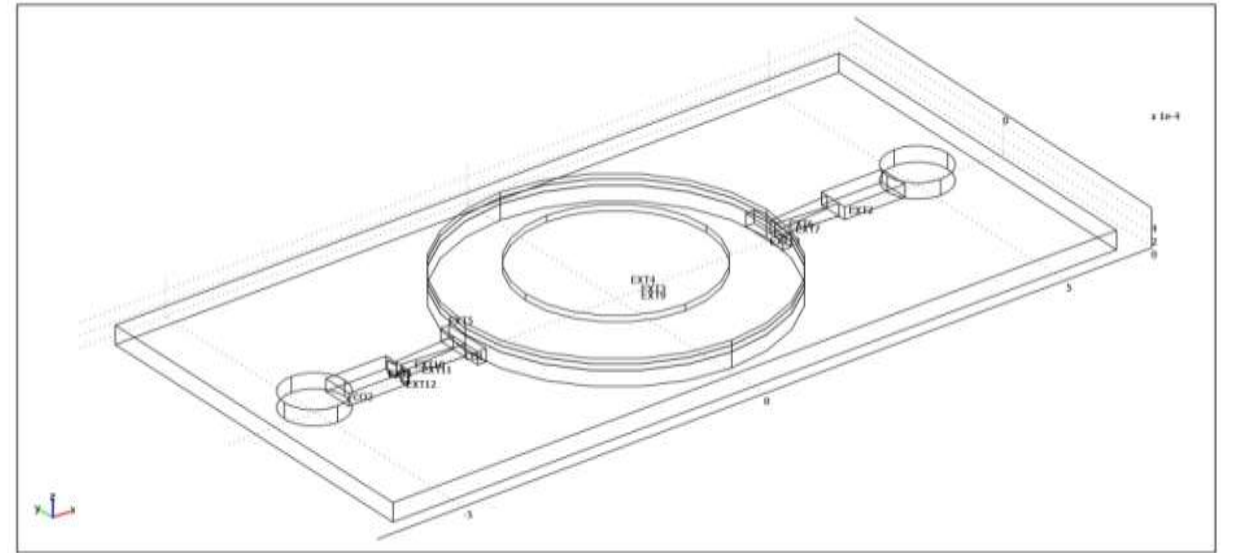


Figure: Design of the micropump



# NOZZLE DIFFUSER MICROPUMP

## Working Principle

- ▶ There are **two modes** of operation of the pump-**expansion mode**, **contraction mode**.
- ▶ In **Expansion mode**, the **volume** of the pumping section **increases more fluid enters** the pumping chamber from the diffuser than the nozzle.
- ▶ In the **Contraction mode**, more **fluid goes out** of the element on the left which now acts as a diffuser, while the element on the right acts as a nozzle.

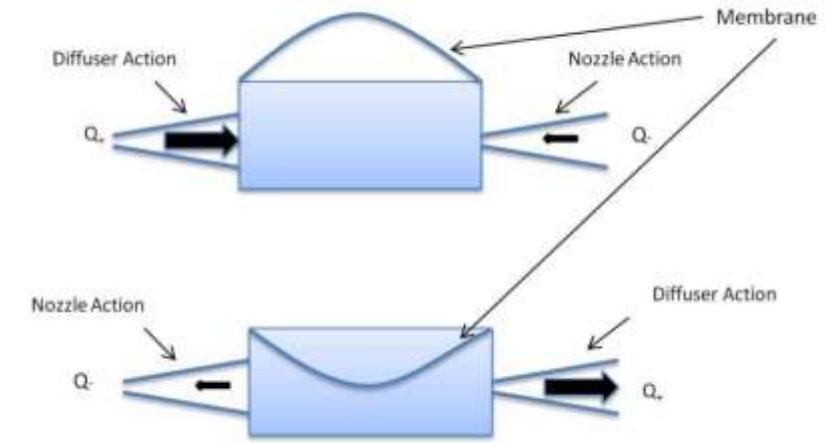


Figure: Modes of operation

## Theoretical Analysis

- ▶ To analyze the working of the diffuser element, **pressure loss coefficient**, **flow rectification efficiency** and **diffuser efficiency** was taken in consideration.
- ▶ The pressure loss coefficient is defined-  $K_d = 1 - \frac{d_a^4}{d_b^4} - C_p$   $K_n = \frac{\Delta p_n}{\rho v_b^2 / 2}$
- ▶ The flow rectification efficiency ( $\epsilon$ ) is given by-  $\epsilon = \frac{Q_+ - Q_-}{Q_+ + Q_-}$
- ▶ The nozzle efficiency of the diffuser is -  $\eta = \frac{K_{n,t}}{K_{d,t}}$
- ▶ **Diffuser angle** should be of **9°**.
- ▶ Less the  $K_d$ , more is the efficiency.

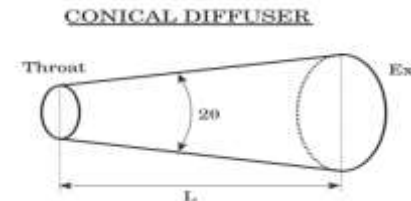


Figure: Conical Diffuser

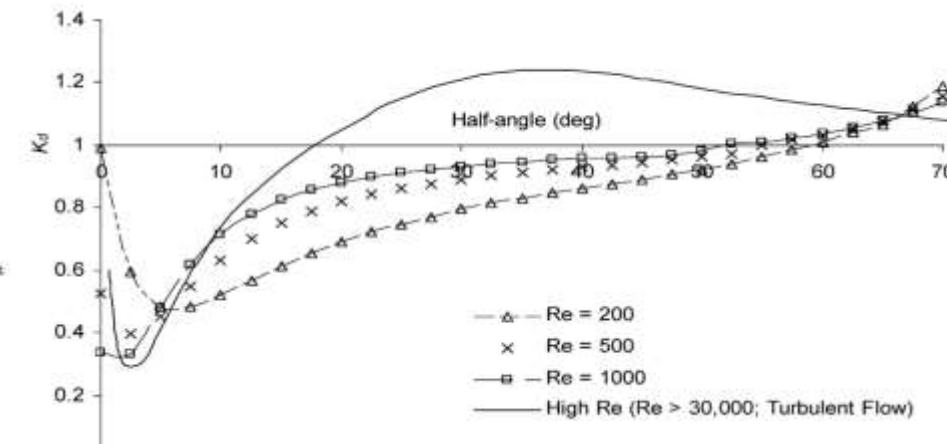


Figure: pressure loss coefficient with half angle

# DEVICE FOR GLAUCOMA TREATMENT

The device can be segregated in two part- Piezoelectric Pressure Sensor and Peristaltic Micropump.

## Peristaltic Micropump

- Dimension of the micropump is 3mm \* 0.25mm.
- Consists of three pumping cells, Microchannels, moving membrane and electrodes.
- Electrostatic force pulls down the diaphragm.
- Fluid chamber expands and fluid starts to flow.
- **Piezoelectric Pressure Sensor-**
- Consists of Stacked layers.
- Size of device is 350 $\mu$ m\*100 $\mu$ m\*1.3 $\mu$ m

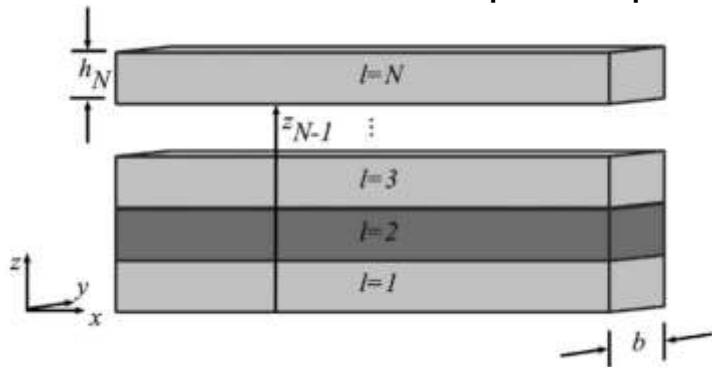


Figure: Piezoelectric laminate beam layer

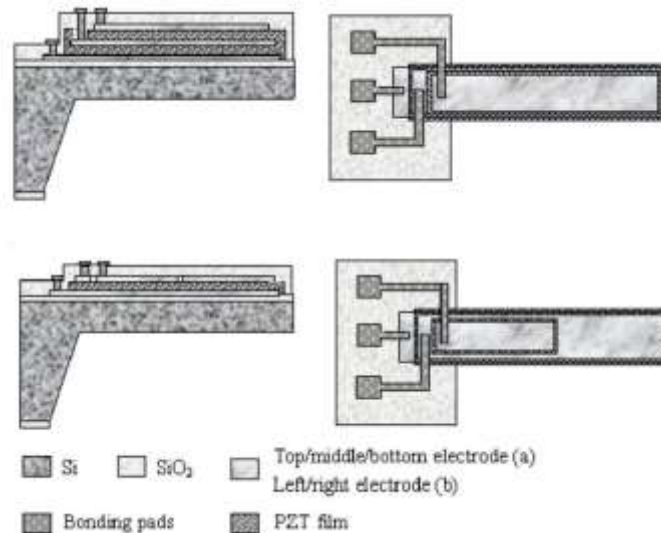


Figure: Bimorph Piezoelectric Sensor

Credit: M. Liu *et al.*, "Piezoelectric Microcantilevers with Two PZT Thin-Film Elements for Microsensors and Microactuators," 2006 1st IEEE International Conference on Nano/Micro Engineered and Molecular Systems, 2006, pp. 775-778.

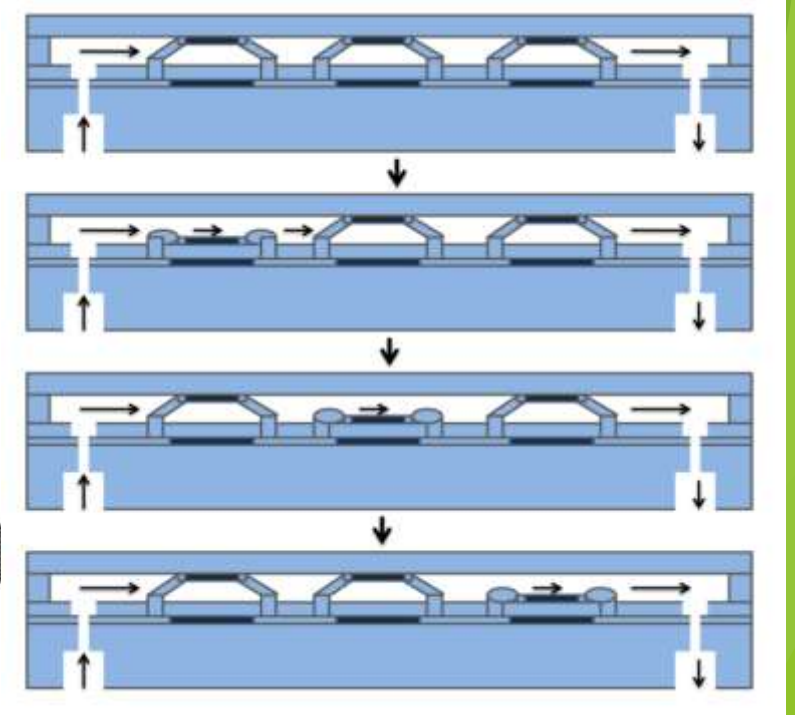
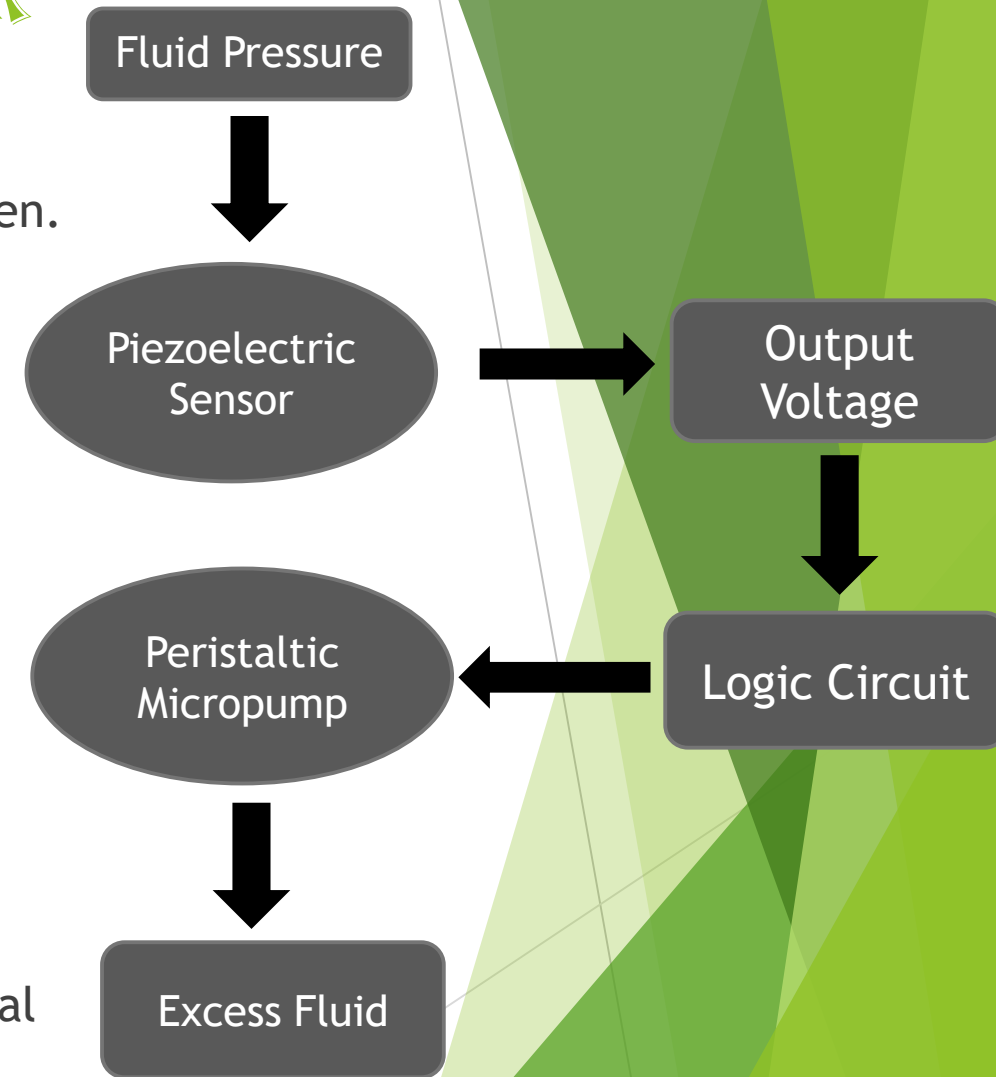


Figure: working of peristaltic micropump  
Credit: MSppt

# DESIGN OF MEMS BASED DEVICE FOR GLAUCOMA TREATMENT

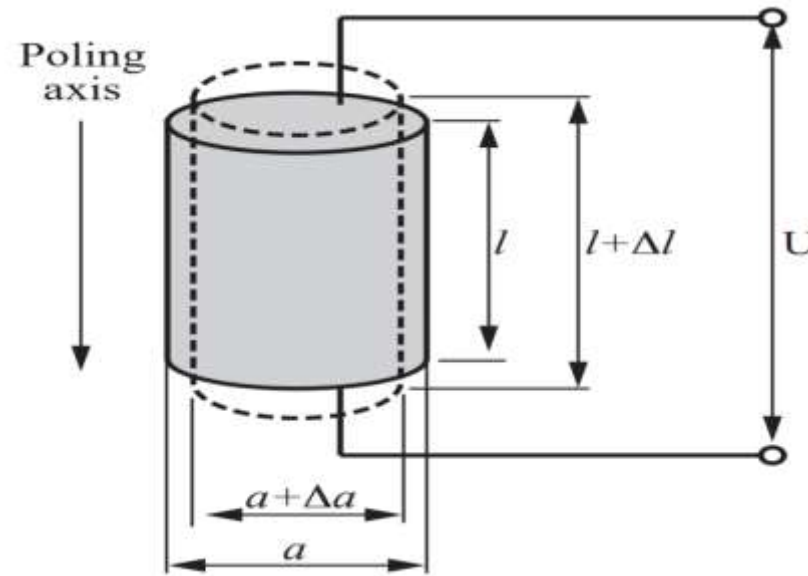
- ▶ The **schematic** and flow chart of **working** of the device is given.
- ▶ The device **self actuates** by the **output voltage** of the **piezoelectric sensor**.
- ▶ A **logic circuit** applies voltage **sequentially** to the different electrodes for operation.
- ▶ How to know the pump will actuate after the pressure increases than a certain range?
- ▶ The **output voltage** of sensor for 25mm Hg and also the **threshold voltage** of membrane known.
- ▶ We thus modulate the output voltage to be greater than the threshold voltage when the pressure increases from the normal limit.



# COMSOL SIMULATION

## ► Actuation Principles

- Special crystals were subject to mechanical tension, they became electrically polarized and the polarization was proportional to the extension - **direct piezoelectric effect**.
- The same phenomenon occurs when an electrical voltage is applied, the material gets deformed - **inverse piezoelectric effect**.
- This serves as the main actuating phenomenon for the pumping mechanism for the micropump.



# COMSOL SIMULATION

## ► Piezoelectric Actuator

Description	Value
Diameter and thickness of the Diaphragm	6mm, 100µm
Diameter and thickness of Brass	6mm, 100µm
Diameter and thickness of the Piezo Material	4mm, 100µm

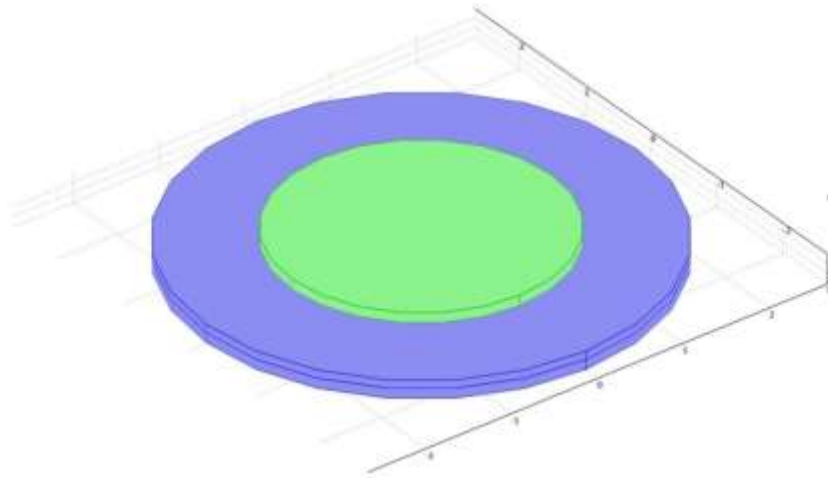
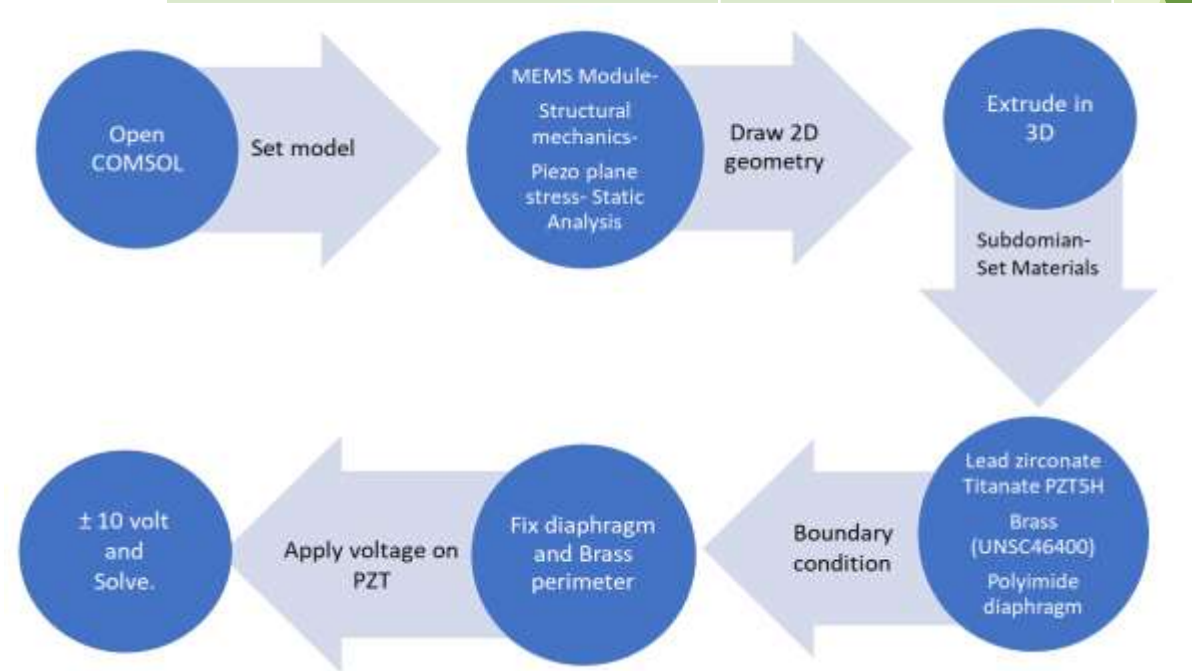


Figure : Design of actuator

Description	Material Used
Diaphragm	PDMS
Piezoelectric Actuator	PZT-5H
Substrate	Brass



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# COMSOL SIMULATION

## Fluid Transport Geometry

Description	Value
Length of the inlet chamber( $l_1$ )	1mm
Length of the diffuser( $l_2$ )	1mm
Chamber Diameter(D)	5mm
Actuator Diameter	3mm
Neck width( $l_3$ )	100 $\mu$ m
Neck width-outflow( $l_4$ )	260 $\mu$ m
Width of chamber	300 $\mu$ m
Top plate thickness	100 $\mu$ m

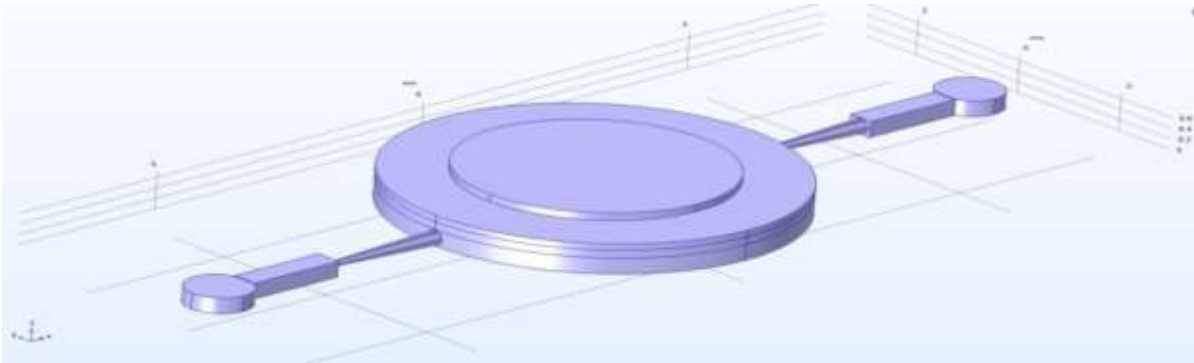


Figure: Design of Fully Developed Nozzle/Diffuser Micropump  
Credit: COMSOLmultiphysics

**Problem formation** (Design variable and performance characteristics)

**Computational formulation** (Pump modeling using pzd and fsi module, governing equations and boundary constraints)

**Simulation and parametric studies** (study of influence of different design parameters on net flow rate)

**Optimal design** (Identification of optimal designed parameters)

**Characterization of micropump**  
(Flow characteristics)



# COMSOL SIMULATION

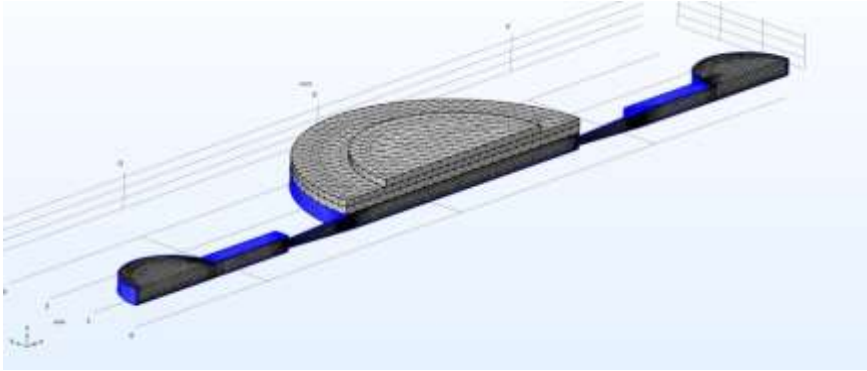


Figure: Mesh formation  
Credit: COMSOL Multiphysics

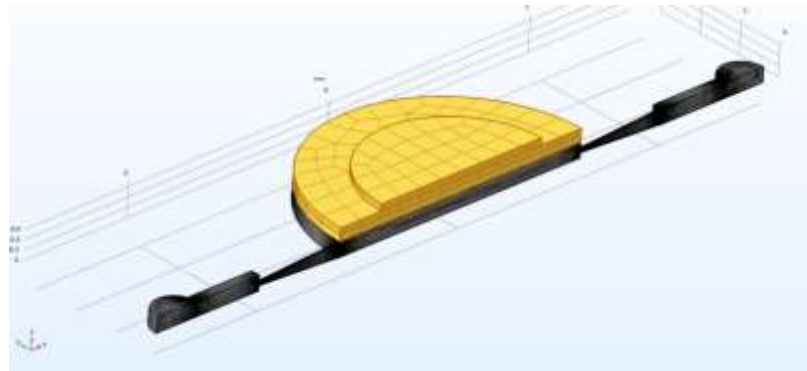


Figure: Swept mesh  
Credit: COMSOL Multiphysics

## ► Boundary Conditions

- The side walls of the diaphragm, membrane and the Piezo disc were fixed.
- For inlet/outlet we have used pressure inlets as boundary conditions.

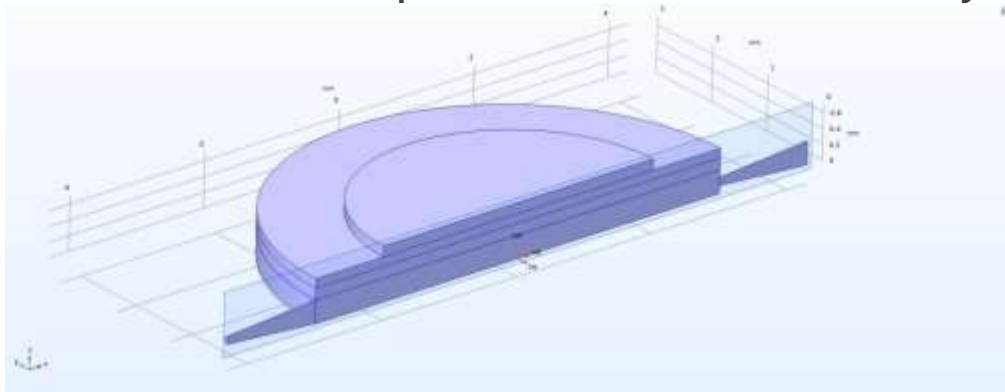


Figure: work / symmetric planes  
Credit: COMSOL Multiphysics

# COMSOL SIMULATION

## ► *Peristaltic Pump 2D Geometry*

Description	Value
Thickness of Actuation Membrane	2μm
Height of Actuation gap	4μm
Thickness of Electrodes	0.5μm
Inlet/Outlet Length	20μm
Height of Microchannel	6μm

## ► *Piezoelectric Sensor*

Material	Thickness
SiO <sub>2</sub>	0.5μm
Aluminum	0.1μm
PZT	0.5μm
Si <sub>3</sub> N <sub>4</sub>	0.1 μm
Length of the sensor	350μm
Breadth of the sensor	100μm

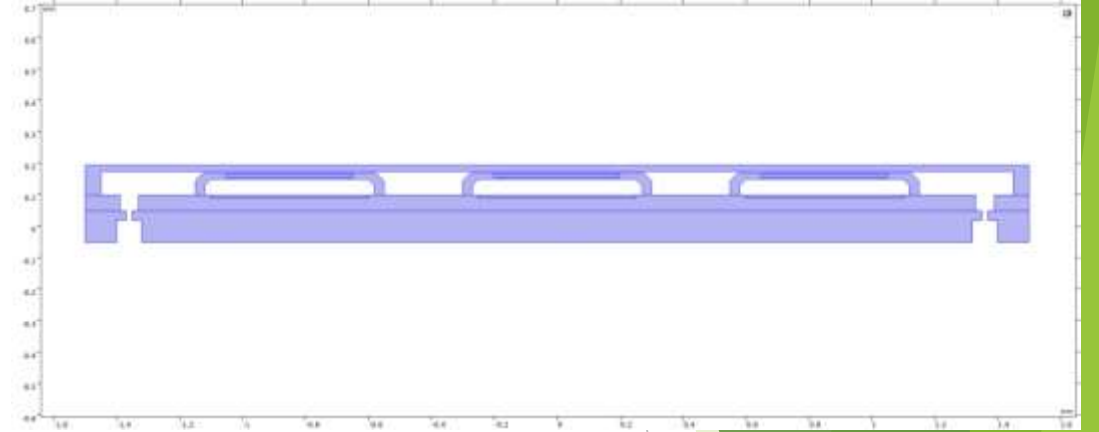


Figure: Design of Peristaltic Micropump  
Credit: COMSOL Multiphysics

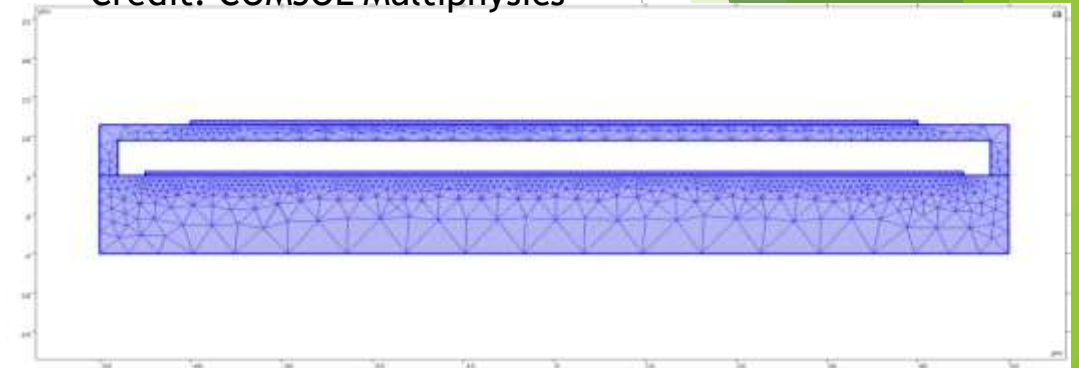


Figure: Mesh Formation

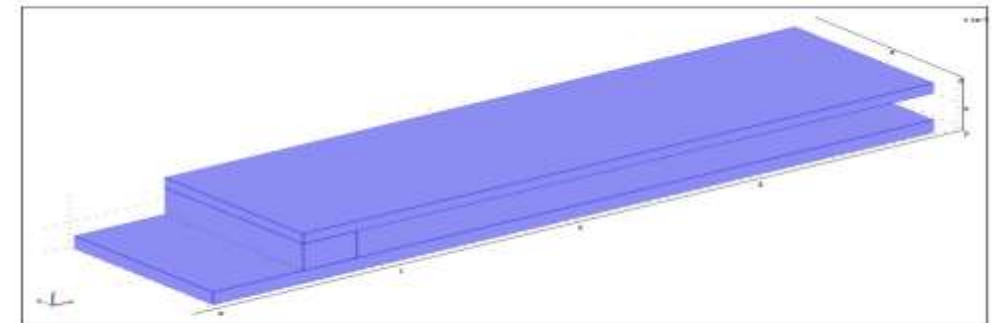


Figure: Piezoelectric Sensor

# RESULTS

## Piezoelectric Simulation-

- ▶ Applying +10volt to the actuator forms a concave surface and bends upwards.
- ▶ Applying -10volt the actuator bends inwards as shown.
- ▶ The graph shows a **linear curve**, thus depicting linear Increase of the diaphragm with the change in voltage.

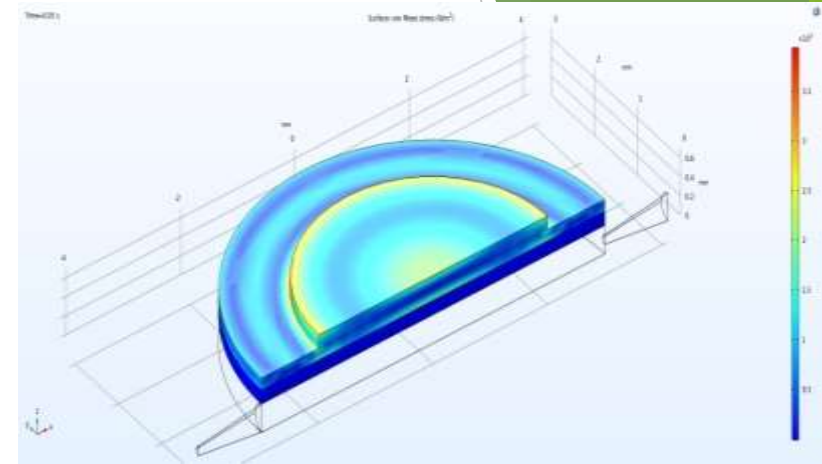


Figure: von-mises stress due to deformation  
Credit: COMSOLmultiphysics

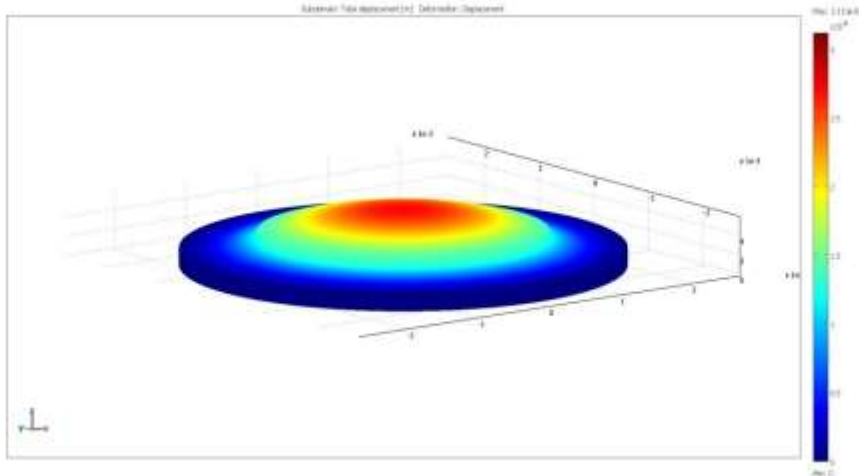


Figure: Piezoelectric actuator simulation  
Credit: COMSOLmultiphysics

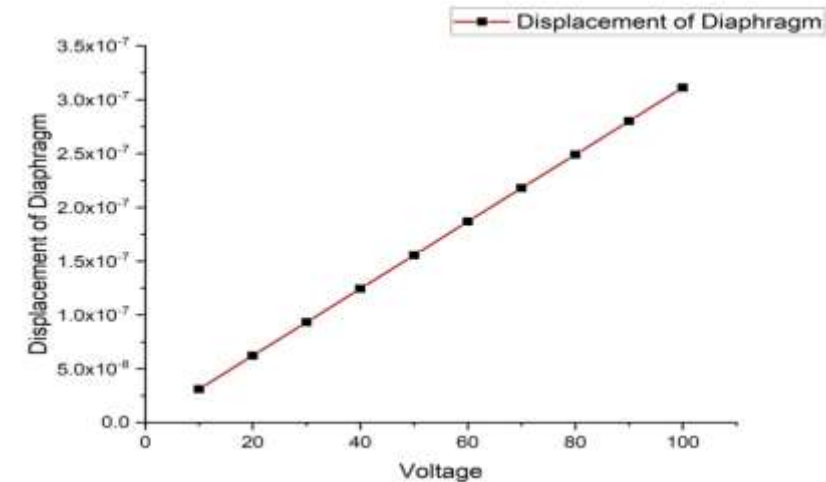


Figure: Diaphragm displacement(m) with voltage(V) plot  
Credit: COMSOLmultiphysics

# RESULTS

## Fluid Transport Simulation-

### ► Inflow characteristics-

- i. It is observed a maximum velocity of  $1.43 \times 10^{-5} \text{ m/s}$  near the neck of the diffuser element. The inflow of the fluid is shown.

### ► Outflow characteristics-

- i. As the top plate is pressed down, the fluid ejecting out of the chamber with a maximum velocity of  $1.54 \times 10^{-5} \text{ m/s}$ .

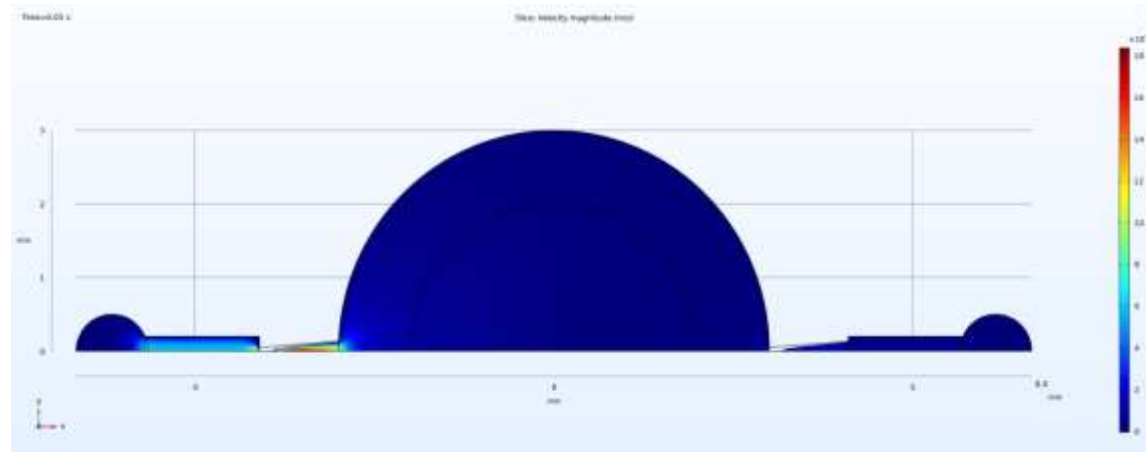


Figure: Simulation of inflow of fluid transport  
Credit: COMSOLmultiphysics software

# RESULTS

## Fluid Streamlines and velocity fields

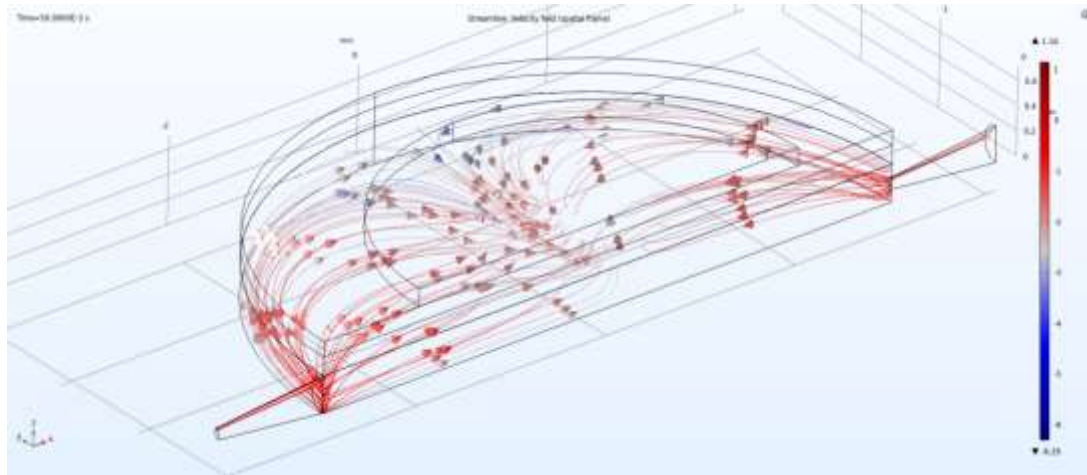


Figure: streamline at time 0.05s (inflow)  
Credit: COMSOL Multiphysics

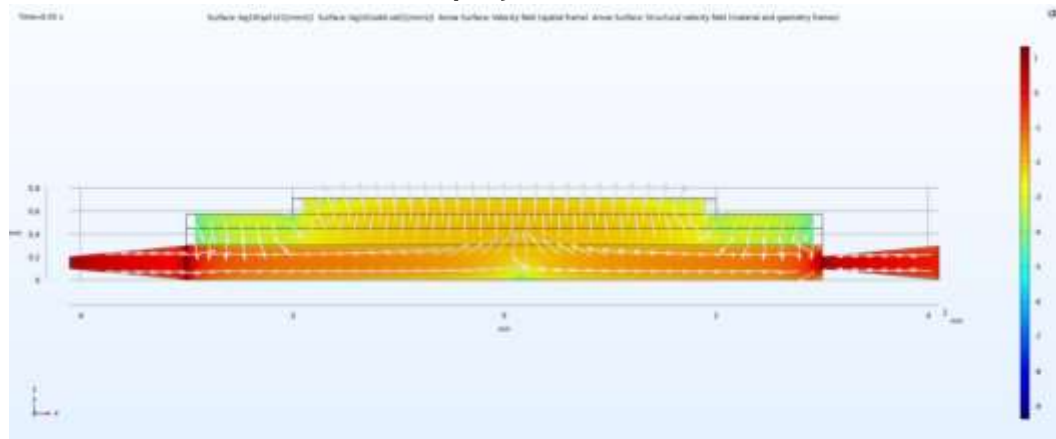


Figure: Flow velocity at time 0.05s (inflow)  
Credit: COMSOL Multiphysics

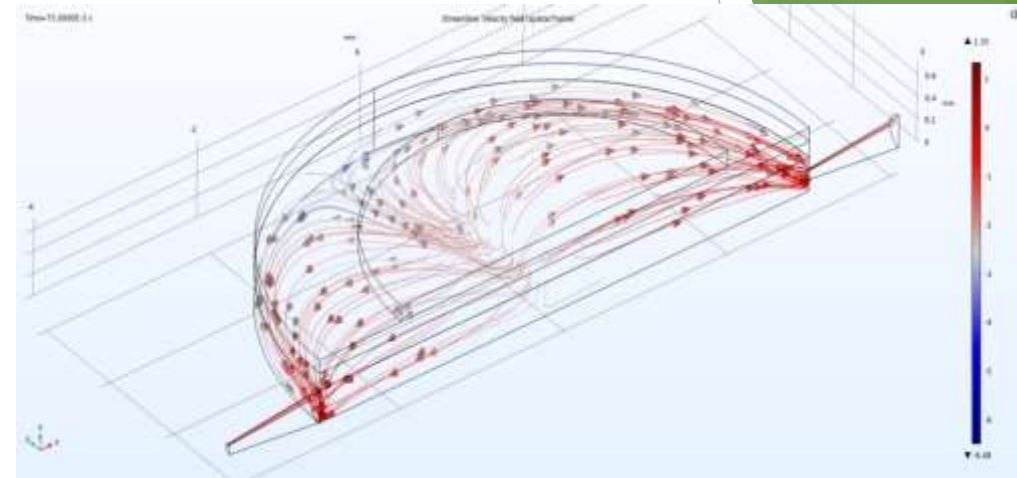


Figure: streamline at time 0.075s (outflow)  
Credit: COMSOL Multiphysics

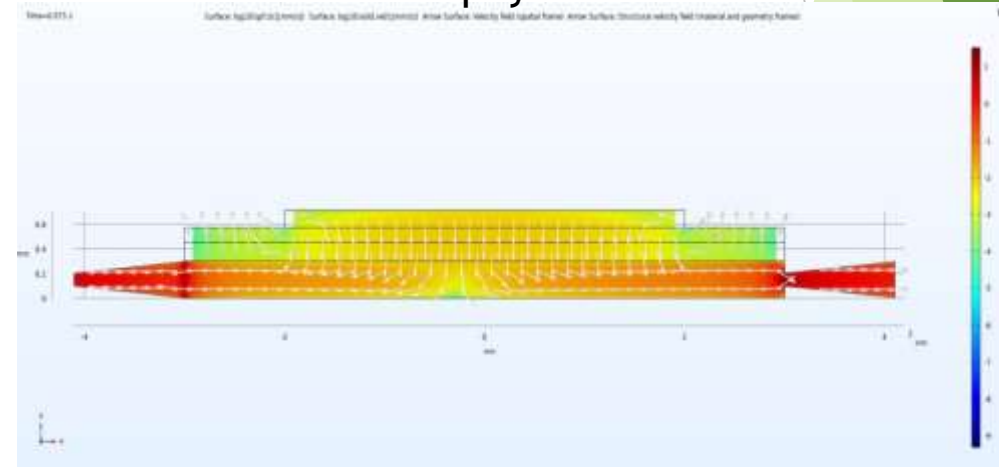


Figure: Flow velocity at time 0.075s (outflow)  
Credit: COMSOL Multiphysics



# RESULTS

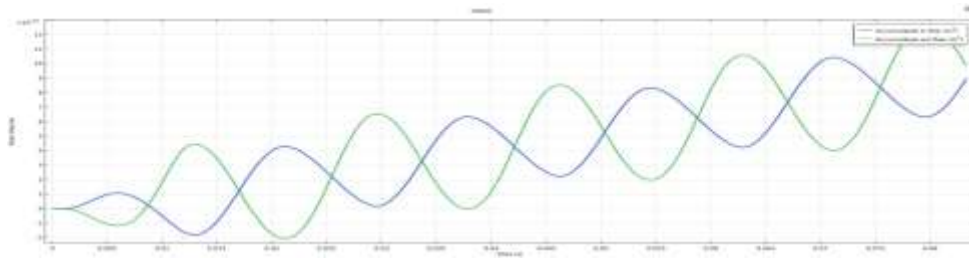


Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser length 0.9mm [COMSOL Multiphysics]

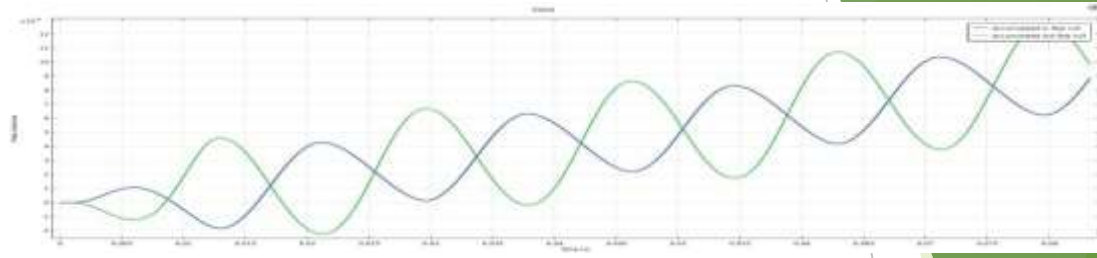


Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser length 1.3mm [COMSOL Multiphysics]



Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser length 1.1mm [COMSOL Multiphysics]

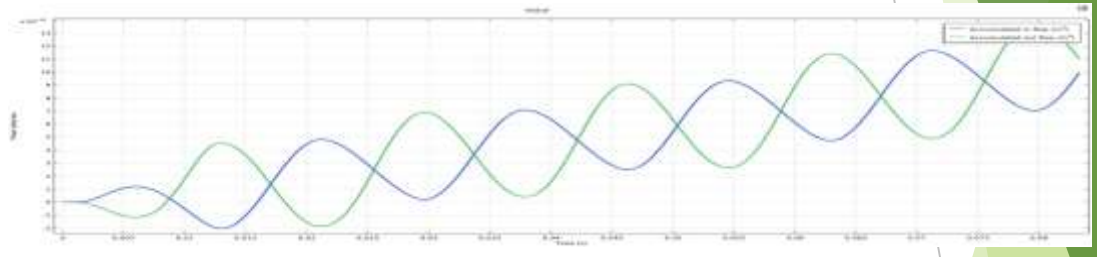


Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser length 1.5mm [COMSOL Multiphysics]

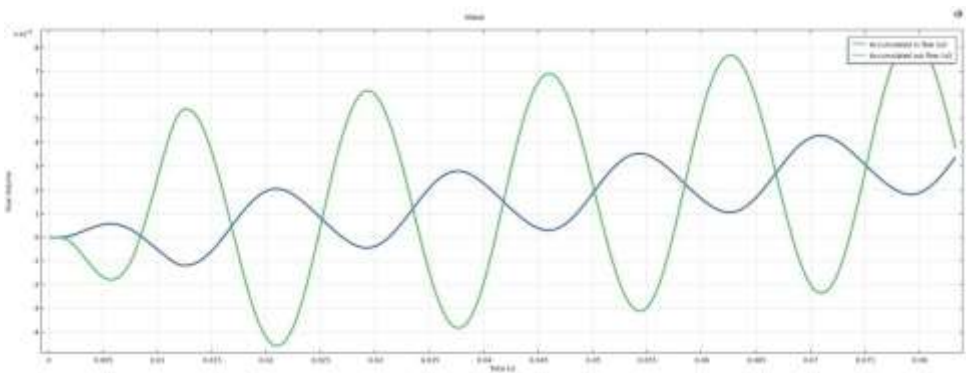


Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser angle  $8^\circ$  [COMSOL Multiphysics]

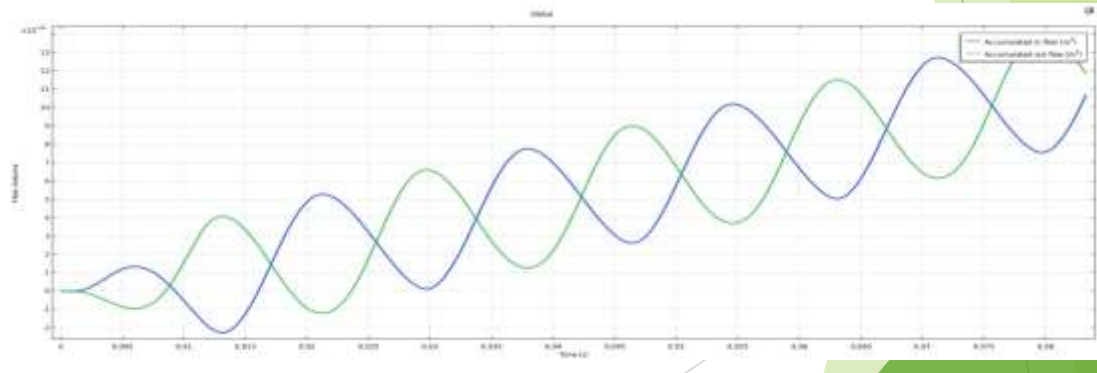


Figure: Accumulated flow volume( $\mu\text{l}$ ) vs. time(s) for diffuser angle  $9^\circ$  [COMSOL Multiphysics]



# RESULTS

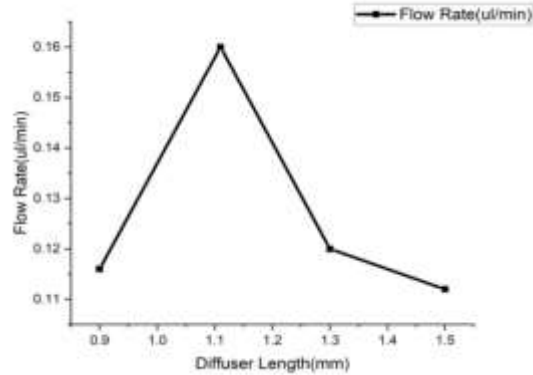


Figure: flow rate( $\mu\text{l}/\text{min}$ ) with diffuser length(mm) plot for blood  
Credit: Origin

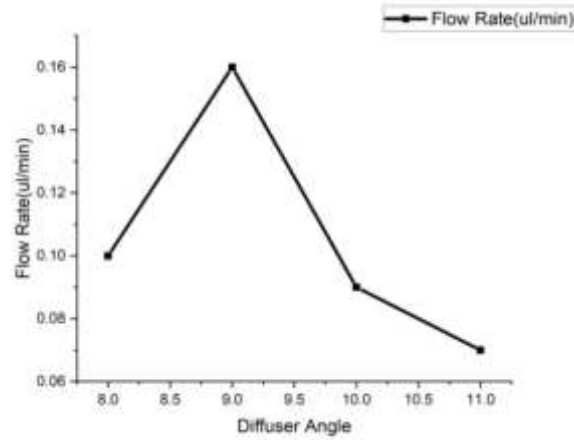


Figure: flow rate( $\mu\text{l}/\text{min}$ ) with diffuser angle( $^\circ$ ) plot for blood  
Credit: Origin

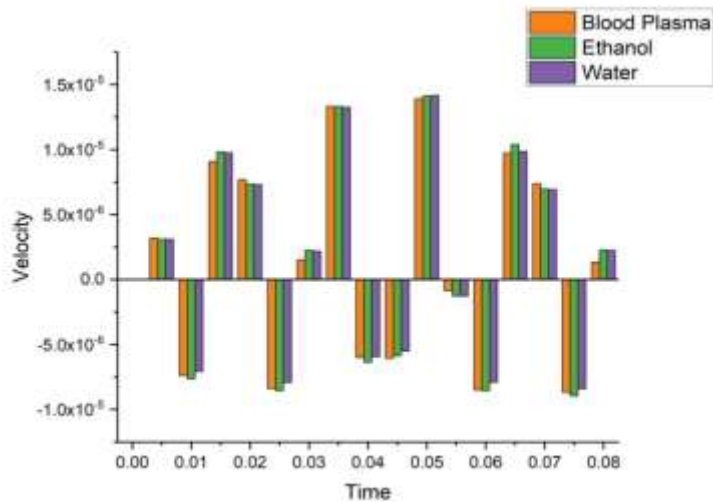


Figure: inlet velocity(m/s) with time(s)  
Credit: Origin

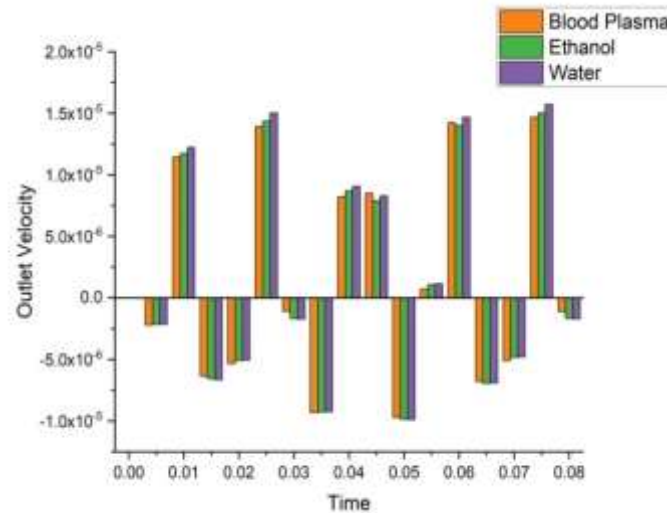


Figure: outlet velocity(m/s) with time(s)  
Credit: Origin

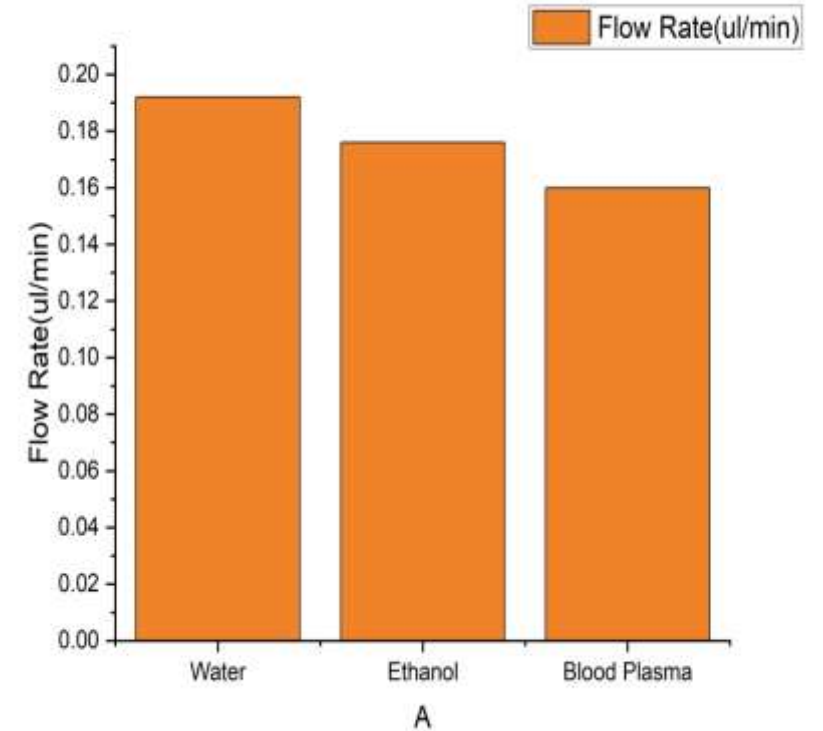
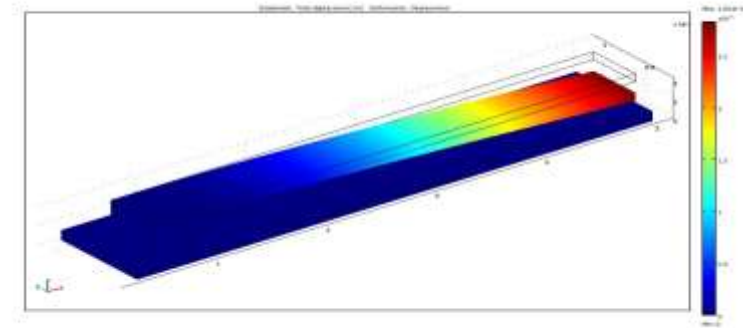
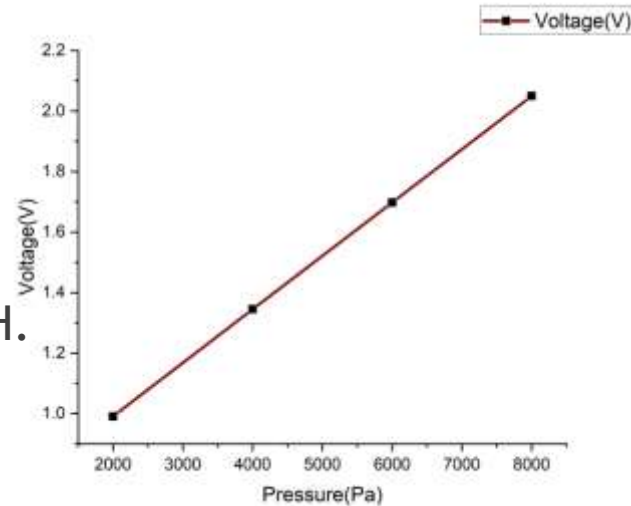


Figure: flow rate (ul/min) of different fluids for optimal geometry  
Credit: Origin

# RESULTS

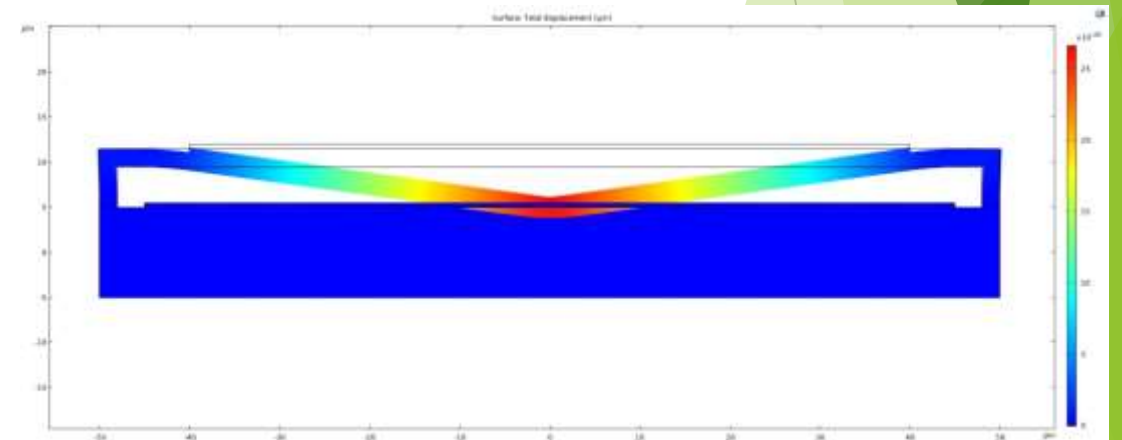
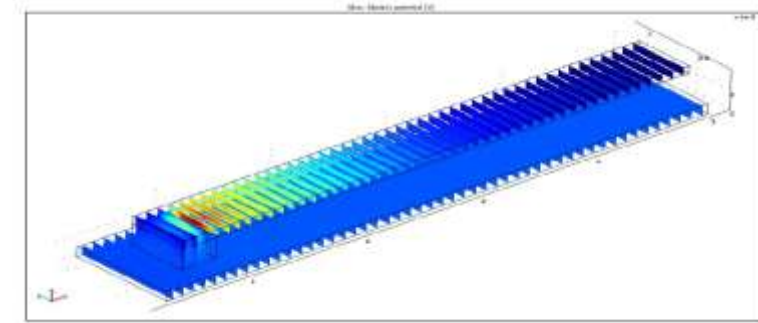
## ► *Piezoelectric Sensor*

- The stacked pressure sensor was simulated and characteristics were studied for PZT-5H.
- Output voltage vs. applied pressure characteristics were measured.



## ► *Peristaltic pump*

- The most important part of the pump is the **moving diaphragm** as actuation depends on its **threshold voltage**.
- The **threshold voltage** of the membrane was seen at **18.5V**, thus voltage of **20 V** was applied on top electrode.



# FUTURE CONSIDERATIONS

## ► Design Improvement

- As we finish designing a single micropump, the design of such can be extended for modifications to increase the flow rate of the pump.

One such design modification is shown.

## ► Fabrication of Structures

- The **process flow** of the fabrication of the MEMS micropump can be given as-
  - Firstly, the a 300µm silicon wafer is **patterned** in the shape of the micropump with the corresponding chamber and two diffuser, inlet-outlet channels using **photolithography**.
  - Then, it was **etched out** to form the required geometry. **Isotropic etching** is to be done for the **conical diffusers** and the **chamber** and the **inlet boundary** will be **anisotropically etched**.
  - Then, the **PDMS diaphragm** was deposited on the wafer and patterned to give the specific shape.
  - Then, the **piezoelectric actuator** with the **brass base plate** was kept on the diaphragm and joined with epoxy/glue resin.

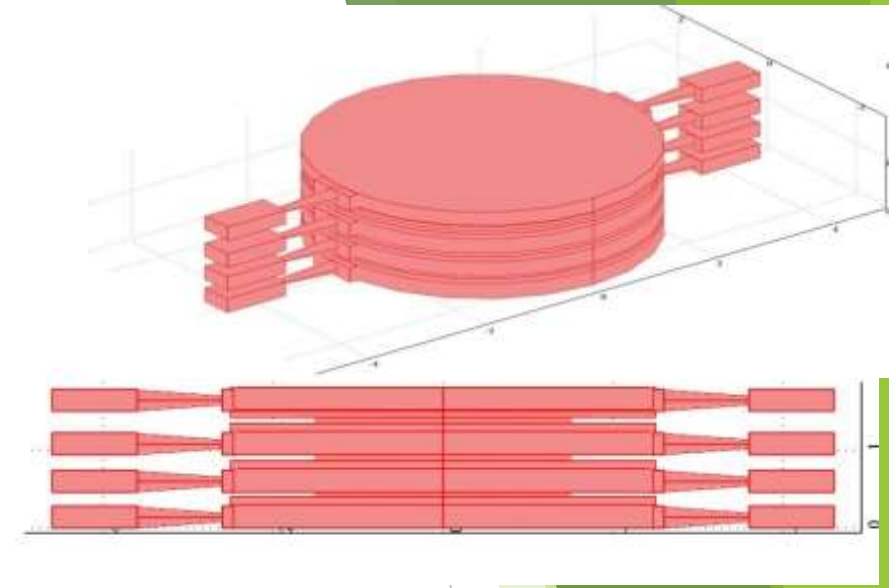


Figure: Design of alternating action micropump  
Credit: COMSOL multiphysics

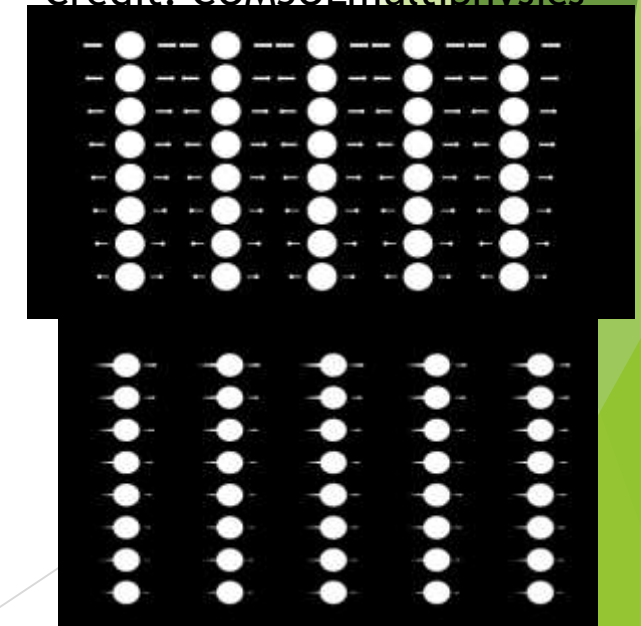


Figure: Masks for fabrication  
Credit: Autocad

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# APPLICATION RANGES

## *Nozzle/Diffuser Micropump*

- ▶ The whole system can have **several application** in medical domain including wounds on outside and inside human body.
- ▶ This device can be attached with the front of the imaging probe for **endoscopy**, and can attach to cuts inside the body after taking samples.
- ▶ For **laparoscopy**, cuts of **1-1.5cm** is made. Our device's dimension is sufficient enough to mitigate the cut for such purpose.

## *Peristaltic Micropump with Pressure sensor*

- ▶ The integrated device can be used to lower down the intraocular pressure thus reducing the chance of glaucoma.
- ▶ The peristaltic micropump alone can also be used for drug delivery purpose specially for glaucoma treatment.

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# Thank You